

TRANSMITTAL OF FORMAL DRAWINGSDocket No.
YOR920030293US1 (16818)In Re Application Of: **Kang Su Choe, et al.****MAY 10 2004**

Serial No.

10/674,647

Filing Date

September 30, 2003

Confirmation No.

Unassigned

Examiner

Unassigned

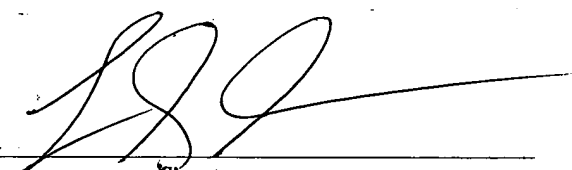
Art Unit

1753Invention: **THIN BURIED OXIDES BY LOW-DOSE OXYGEN IMPLANTATION INTO MODIFIED SILICON**

Address to:

**Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450**

Transmitted herewith are:

6 sheets of formal drawing(s) for this application.☒ Each sheet of drawing indicates the identifying indicia suggested in 37 CFR Section 1.84(c).
Signature
**Leslie S. Szivos, Ph.D.
Registration No. 39,394
SCULLY, SCOTT, MURPHY & PRESSER
400 Garden City Plaza
Garden City, New York 11530
(516) 742-4343**Dated: **May 7, 2004****I certify that this document and attached formal drawings
are being deposited on 5/7/2004 with the
U.S. Postal Service as first class mail under 37 C.F.R. 1.8
and addressed to the Commissioner for Patents, P.O. Box
1450, Alexandria, VA 22313-1450.**
*Signature of Person Mailing Correspondence***Leslie S. Szivos, Ph.D.***Typed or Printed Name of Person Mailing Correspondence*